

FYS 4230 Design and modeling of Mikro- og nanosystemer
 Fall 2009
 Book: S.D.Senturia "Microsystem Design"

Kapittel		Sections that are not curriculum / pensum
1	Introduction	
2	An approach to MEMS design	
3	Microfabrication	not 3.2.1.2 3.2.4 3.2.6.3 3.2.6.5 3.2.7.3 3.3.3 3.3.6 3.3.7
8	Elasticity	not 8.3
9	Structures	not 9.2.1 9.2.2 9.4 9.6 9.7 9.8
13	Fluids	Not derivation of Navier Stokes dvs 13.2.4, 13.2.5., 13.2.7 And not 13.2.8 13.3.3 13.3.4 13.4 13.5.5
14	Electronics Only fig 14.3 and section 14.4 "Diffused resistor"	
18	A piezoresistive pressure sensor	not 18.3.1 18.3.3 18.3.4
19	A capacitive accelerometer	not 19.3.1 19.3.2 19.3.3

		19.3.4 19.4.3 19.5
20	Electrostatic projection displays	not 20.3 20.4
22	Microsystems for DNA amplification	not 22.4 22.5